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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/779,904	02/17/2004	Masahiro Ishida	02008.071003	9608

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EXAMINER

LOUIE, OSCAR A

ART UNIT	PAPER NUMBER
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2136

NOTIFICATION DATE	DELIVERY MODE
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07/31/2008

ELECTRONIC

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Notice of the Office communication was sent electronically on above-indicated "Notification Date" to the following e-mail address(es):

docketing@oshaliang.com
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Office Action Summary	Application No. 10/779,904	Applicant(s) ISHIDA ET AL.	
	Examiner OSCAR A. LOUIE	Art Unit 2136	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 30 May 2008.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 4, 16 and 27 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 4, 16 and 27 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on _____ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|--|---|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413) |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | Paper No(s)/Mail Date. _____ |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO/SB/08) | 5) <input type="checkbox"/> Notice of Informal Patent Application |
| Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

This first non-final action is in response to the Request for Continued Examination filing of 05/30/2008. Claims 4, 16, & 27 are pending and have been considered as follows.

Claim Objections

1. Claims 4, 16, & 27 are objected to because of the following informalities:
 - Claim 4 line 1 recites the term “for” which should be “...of...”;
 - Claims 16 & 27 line 1 recite the term “for” which should be “...configured to...”;
 - Claims 4, 16, & 27 line 9 recite the term “when” which should be “...once...”;

Appropriate correction is required.

Claim Rejections - 35 USC § 101

2. 35 U.S.C. 101 reads as follows:

Whoever invents or discovers any new and useful process, machine, manufacture, or composition of matter, or any new and useful improvement thereof, may obtain a patent therefor, subject to the conditions and requirements of this title.

Claims 16 & 27 are rejected under 35 U.S.C. 101 because the claimed invention is directed to non-statutory subject matter.

- Claims 16 & 27 recite “a fault analysis apparatus for presuming a fault location of a semiconductor IC” comprising “means for” which appear to be nothing more than computer program modules, thereby invoking 35 U.S.C. 101 as non-statutory subject matter;

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Descriptive material can be characterized as either “functional descriptive material” or “nonfunctional descriptive material.” In this context, “functional descriptive material” consists of data structures and computer programs which impart functionality when employed as a computer component. (The definition of “data structure” is “a physical or logical relationship among data elements, designed to support specific data manipulation functions.” The New IEEE Standard Dictionary of Electrical and Electronics Terms 308 (5th ed. 1993).) “Nonfunctional descriptive material” includes but is not limited to music, literary works, and a compilation or mere arrangement of data.

*Both types of “descriptive material” are nonstatutory when claimed as descriptive material per se, 33 F.3d at 1360, 31 USPQ2d at 1759. When functional descriptive material is recorded on some computer-readable medium, it becomes structurally and functionally interrelated to the medium and will be statutory in most cases since use of technology permits the function of the descriptive material to be realized. Compare In re Lowry, 32 F.3d 1579, 1583-84, 32 USPQ2d 1031, 1035 (Fed. Cir. 1994)(discussing patentable weight of data structure limitations in the context of a statutory claim to a data structure stored on a computer readable medium that increases computer efficiency) and >In re< Warmerdam, 33 F.3d *>1354,< 1360-61, 31 USPQ2d *>1754,< 1759 (claim to computer having a specific data structure stored in memory held statutory product-by-process claim) with Warmerdam, 33 F.3d at 1361, 31 USPQ2d at 1760 (claim to a data structure per se held nonstatutory)*

Claim Rejections - 35 USC § 103

3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

4. Claims 4, 16, & 27 are rejected under 35 U.S.C. 103(a) as being unpatentable over Sugasawara (US-6043672-A).

Claims 4 & 16:

Sugasawara discloses a fault analysis method & apparatus for presuming a fault location of a semiconductor IC comprising,

- “applying a power supply voltage to said semiconductor IC” (i.e. “A selectable power supply line for providing power to a particular section of the integrated circuit is activated by an enable signal provided to a selectable power supply switch coupled to the selectable power supply line”) [column 3 lines 28-32];
- “supplying a test pattern sequence having a plurality of test patterns to said semiconductor IC” (i.e. “Test development strategies include functional test wherein automatic test equipment (ATE) test programs are performed in which the circuit under test is stimulated with specified inputs while the outputs are monitored to determine if they correspond with simulated logic values”) [column 1 lines 54-58];
- “the electrical potentials at the one or more locations are expected to change when the test pattern sequence is supplied” (i.e. “Defects in integrated circuits take many forms, some of which are test pattern sensitive...Quiescent current tests differ in that current is sensed rather than voltage, providing a simple means to monitor the entire circuit or portions thereof for over-current conditions”) [column 1 lines 64-65 & column 2 lines 25-28];
- “measuring a transient power supply current generated on said semiconductor IC in accordance with the change of said test pattern” (i.e. “Once halted (i.e., no transistor state switching is occurring) the power supply of the device under test is measured by the ATE and the resulting value is compared to predetermined reference values or test limits”) [column 2 lines 14-18];

- “determining whether said transient current shows abnormality or not” (i.e. “the device under test is measured by the ATE and the resulting value is compared to predetermined reference values or test limits. Such quiescent current tests are effective in detecting many faults that would otherwise not be found by other test strategies”) [column 2 lines 16-20];
- “presuming a fault location out of said fault location list based on said test pattern sequence” (i.e. “This approach has typically included measuring current in a region of the integrated circuit, cutting lines to sections within the same region other than the section of interest, and then taking a additional measurements of current in the region”) [column 2 lines 49-53];
- “where the transient power supply current shows abnormality and said fault location list” (i.e. “In order to isolate the defective area of an integrated circuit, a failure analysis engineer seeks to determine which section of the integrated circuit is responsible for unusual current levels”) [column 2 lines 38-41];
- “said transient power supply current is determined to be abnormal in case time integral of said transient power supply current is over a predetermined value in said step of determining” (i.e. “In order to isolate the defective area of an integrated circuit, a failure analysis engineer seeks to determine which section of the integrated circuit is responsible for unusual current levels”) [column 2 lines 38-41];

but Sugasawara does not explicitly disclose,

- “storing a fault location list for the test pattern sequence,” although Sugasawara does suggest an automated test equipment that would store test pattern sequences and which portions of the semiconductor integrated circuit have been isolated for testing, as recited below;
- “wherein the fault location list includes one or more locations of components in said IC,” although Sugasawara does suggest several components of a semiconductor integrated circuit that are tested for defects, as recited below;

however, Sugasawara does disclose,

- “automated test equipment (ATE)” [column 5 line 11];
- “CMOS circuits use complementary p-channel metal-oxide-semiconductor field-effect (PMOS) transistors and n-channel metal-oxide-semiconductor field-effect (NMOS) transistors... Gate oxide defects, drain to source current leaks (punch-through), and p-n junction current leaks (such as drain or source to diffusion current leaks)” [column 1 lines 36-39, 66-67 & column 2 line 1];

Therefore, it would have been obvious for one of ordinary skill in the art at the time of the applicant’s invention to include, “storing a fault location list for the test pattern sequence” and “wherein the fault location list includes one or more locations of components in said IC,” in the invention as disclosed by Sugasawara since predetermined reference values or test limits would typically be stored within the testing device in order to be compared to the resulting value(s).

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Claim 27:

Sugasawara discloses a fault analysis method & apparatus for presuming a fault location of a semiconductor IC comprising,

- “a means for applying a power supply voltage to said semiconductor IC” (i.e. “A selectable power supply line for providing power to a particular section of the integrated circuit is activated by an enable signal provided to a selectable power supply switch coupled to the selectable power supply line”) [column 3 lines 28-32];
- “a means for supplying a test pattern sequence comprising a plurality of test patterns to said semiconductor IC” (i.e. “Test development strategies include functional test wherein automatic test equipment (ATE) test programs are performed in which the circuit under test is stimulated with specified inputs while the outputs are monitored to determine if they correspond with simulated logic values”) [column 1 lines 54-58];
- “the electric potentials at the one or more locations are expected to change when the test pattern sequence is supplied” (i.e. “Defects in integrated circuits take many forms, some of which are test pattern sensitive...Quiescent current tests differ in that current is sensed rather than voltage, providing a simple means to monitor the entire circuit or portions thereof for over-current conditions”) [column 1 lines 64-65 & column 2 lines 25-28];
- “a means for measuring a transient power supply current generated on said semiconductor IC in accordance with the change of said test pattern” (i.e. “Once halted (i.e., no transistor state switching is occurring) the power supply of the device under test is measured by the ATE and the resulting value is compared to predetermined reference values or test limits”) [column 2 lines 14-18];

- “a means for determining that said transient current is abnormal in case time integral of said transient power supply current is over a predetermined value” (i.e. “the device under test is measured by the ATE and the resulting value is compared to predetermined reference values or test limits. Such quiescent current tests are effective in detecting many faults that would otherwise not be found by other test strategies”) [column 2 lines 16-20];
- “a means for presuming a fault location out of said fault location list based on said test pattern sequence” (i.e. “This approach has typically included measuring current in a region of the integrated circuit, cutting lines to sections within the same region other than the section of interest, and then taking a additional measurements of current in the region”) [column 2 lines 49-53];
- “where the transient power supply current shows abnormality and said fault location list” (i.e. “In order to isolate the defective area of an integrated circuit, a failure analysis engineer seeks to determine which section of the integrated circuit is responsible for unusual current levels”) [column 2 lines 38-41];

but Sugasawara does not explicitly disclose,

- “a means for storing a fault location list for the test pattern sequence,” although Sugasawara does suggest an automated test equipment that would store test pattern sequences and which portions of the semiconductor integrated circuit have been isolated for testing, as recited below;

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- “wherein the fault location list includes one or more locations of components in said IC,” although Sugasawara does suggest several components of a semiconductor integrated circuit that are tested for defects, as recited below;

however, Sugasawara does disclose,

- “automated test equipment (ATE)” [column 5 line 11];
- “CMOS circuits use complementary p-channel metal-oxide-semiconductor field-effect (PMOS) transistors and n-channel metal-oxide-semiconductor field-effect (NMOS) transistors... Gate oxide defects, drain to source current leaks (punch-through), and p-n junction current leaks (such as drain or source to diffusion current leaks)” [column 1 lines 36-39, 66-67 & column 2 line 1];

Therefore, it would have been obvious for one of ordinary skill in the art at the time of the applicant’s invention to include, “a means for storing a fault location list for the test pattern sequence” and “wherein the fault location list includes one or more locations of components in said IC,” in the invention as disclosed by Sugasawara since predetermined reference values or test limits would typically be stored within the testing device in order to be compared to the resulting value(s).

Response to Arguments

5. Applicant's arguments, see pages 5-7, filed 05/30/2008, with respect to the rejection(s) of claim(s) 4, 16, & 27 under 35 U.S.C. 103(a) have been fully considered and are persuasive.

Therefore, the rejection has been withdrawn. However, upon further consideration, a new ground(s) of rejection is made in view of a different interpretation of the previously applied prior art of record.

- The examiner notes that the "fault location list" as recited in the applicant's claims appears to encompass "a set of defective signal lines" as recited by the applicant's Specification on pages 52, 53, & 55; thus, any part of a semiconductor integrated circuit that is tested for defects would apply;

Conclusion

6. The prior art made of record and not relied upon is considered pertinent to the applicant's disclosure.

- a. Schinabeck et al. (US-4646299) – applying and monitoring programmed test signals during automated testing of electronic circuits;
- b. Harwood et al. (US-5101152) – integrated circuit transfer test device system utilizing lateral transistors;
- c. Luciani et al. (US-5182717) – device for testing a network of components in particular an electronic circuit;

- d. Ozaki et al. (US-5331275) – probing device and system for testing an integrated circuit;
- e. Shida et al. (US-5592100) – method for detecting an IC defect using charged particle beam;
- f. Teene (US-5726997) – apparatus and method for testing of integrated circuits;
- g. Nikawa (US-5804980) – method and system for testing an interconnection in a semiconductor integrated circuit;
- h. Sanada (US-5864566) – Fault block detecting system using abnormal current and abnormal data output;
- i. Gattiker et al. (US- 6175244) – current signatures for IDDQ testing;

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Oscar Louie whose telephone number is 571-270-1684. The examiner can normally be reached Monday through Thursday from 7:30 AM to 4:00 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nasser Moazzami, can be reached at 571-272-4195. The fax phone number for Formal or Official faxes to Technology Center 2100 is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private

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PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

OAL
07/29/2008

/Nasser G Moazzami/
Supervisory Patent Examiner, Art Unit 2136